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Docket No.: 21776-00044-US  
(PATENT) Back

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:  
Takahisa Nitta, et al.

Conf. No.

Application No.: 09/436,637

Group Art Unit: 6921

Filed: November 9, 1999

Examiner: C. Cooley

For: CHEMICAL SUPPLY SYSTEM

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AMENDMENT UNDER 37 CFR 1.116

Box AF  
Commissioner for Patents  
Washington, DC 20231

March 10, 2003

Dear Sir:

In response to the Office Action dated December 10, 2002 (Paper No. 13), finally rejecting claims 1-15, please amend the above-identified U.S. patent application as follows:

In the Claims

Please amend claims 1 and 8 as follows:

1. (Twice Amended) A chemical supply system for supplying a mixture solution to a chemical treatment chamber, wherein said mixture solution includes a liquid chemical mixed and diluted with a solvent, said chemical supply system comprising:
  - at least one chemical reservoir that is easy to carry, wherein said liquid chemical is stored in said chemical reservoir at a high concentration;
  - a piping system in which said solvent flows, wherein said piping system includes a discharge portion for said mixture solution at an end portion thereof; and
  - a chemical supply means for feeding out a predetermined quantity of said liquid chemical from said chemical reservoir into a connecting pipe;
  - a chemical discharging means connecting said connecting pipe to said piping system and

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01 FC:1201 84.00 CH  
02 FC:1202 18.00 CH